

ABSTRACT

SUBSTRATE HOLDING APPARATUS AND METHOD OF MANUFACTURING A DRIVE RING

5 The present invention relates to a substrate holding apparatus used to polish a surface of the substrate by pressing the substrate against a polishing tool, such as a polishing pad. Further, the present invention relates to a method of manufacturing a drive ring used for the substrate holding apparatus. A substrate holding apparatus (1) includes a polishing head body (10), a drive ring (81) disposed below the polishing head
10 body (10), and a retainer ring (40) fixed to the drive ring (81). The drive ring (81) has an annular contact surface (81a) that contacts the retainer ring (40). A flatness in the circumferential direction of the contact surface (81a) is 4.6 μm or less. The flatness represents a difference in a height between the highest position and the lowest position of the contact surface (81a).

15 Figure 3